

SiW Ecal EUDET Module

From the TDR to the
Demonstrator
and beyond

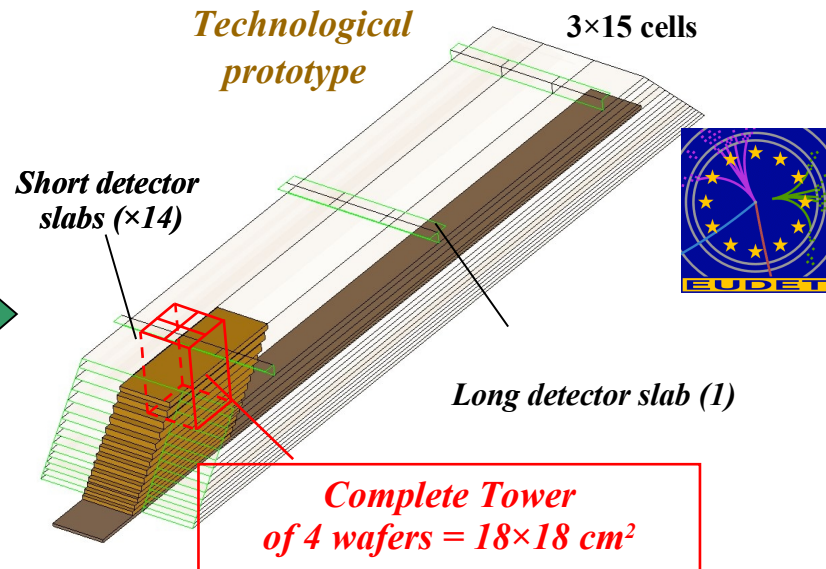
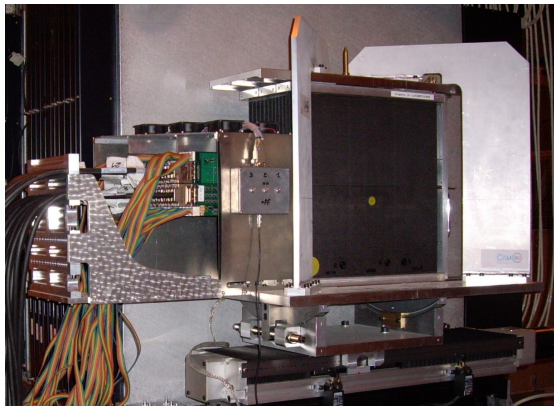
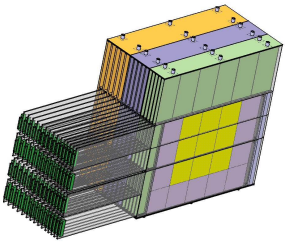
Roman Pöschl
LAL Orsay

To learn more

<http://flc.web.lal.in2p3.fr/poeschl/siwecal.html>

EUDET Prototype

- **Logical continuation** to the physical prototype study which validated the main concepts : alveolar structure , slabs, gluing of wafers, integration
- Techno. Proto : study and validation of most of **technological solutions** wich could be used for the final detector (moulding process, cooling system, wide size structures,...)
- Taking into account **industrialization aspect** of process
- First **cost** estimation of one module



- **3 structures : $24 X_0$**
($10 \times 1,4\text{mm} + 10 \times 2,8\text{mm} + 10 \times 4,2\text{mm}$)
- **sizes : $380 \times 380 \times 200 \text{ mm}^3$**
- **Thickness of slabs : 8.3 mm**
($W=1,4\text{mm}$)
- **VFE outside detector**
- **Number of channels : $9720 (10 \times 10 \text{ mm}^2)$**
- **Weight : $\sim 200 \text{ Kg}$**

[sukuba]

- **1 structure : $\sim 23 X_0$**
($20 \times 2,1\text{mm} + 9 \times 4,2\text{mm}$)
- **sizes : $1560 \times 545 \times 186 \text{ mm}^3$**
- **Thickness of slabs : 6 mm**
($W=2,1\text{mm}$)
- **VFE inside detector**
- **Number of channels : $45360 (5 \times 5 \text{ mm}^2)$**
- **Weight : $\sim 700 \text{ Kg}$**

The groups working on the EUDET Electromagnetic Calorimeter



- What we call “EUDET Module” is in fact the next SiW Ecal CALICE Prototype
- Financial support by EU but largest fraction of funding still from “Calice” resources!!!!

Time Scale of Project

~Today Spring 2009 2009 Summer/Autmun 2009 2010

← Studies on mechanical Integration and DAQ →

Tests avec ASU1

Tests avec ASU2

Design
of Prototype
concluded

Assembly
and studies
with
Demonstrateur

'ASU 1':
SPIROC2/SKIROC
with
FEV7

EUDET:
Deadline,
Alveolar
Structures
and ASU 1

ASU2:
SPIROC2
with
FEV8

EUDET-Memo-2008-07



ECAL Si/W – Design and Fabrication of moulds
for the EUDET Module

M.Anduze, R. Poeschl

July 01, 2008

Covering aspects of the alveolar
structures

TDR of SiW EUDET Module



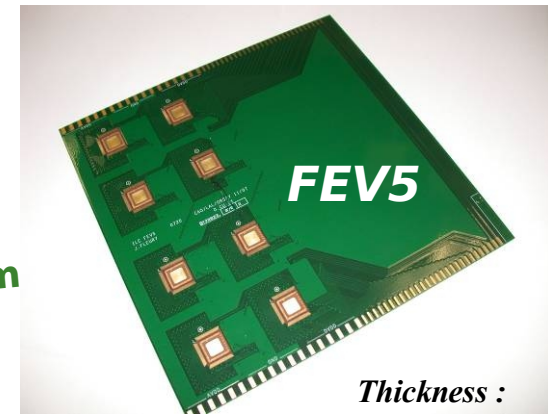
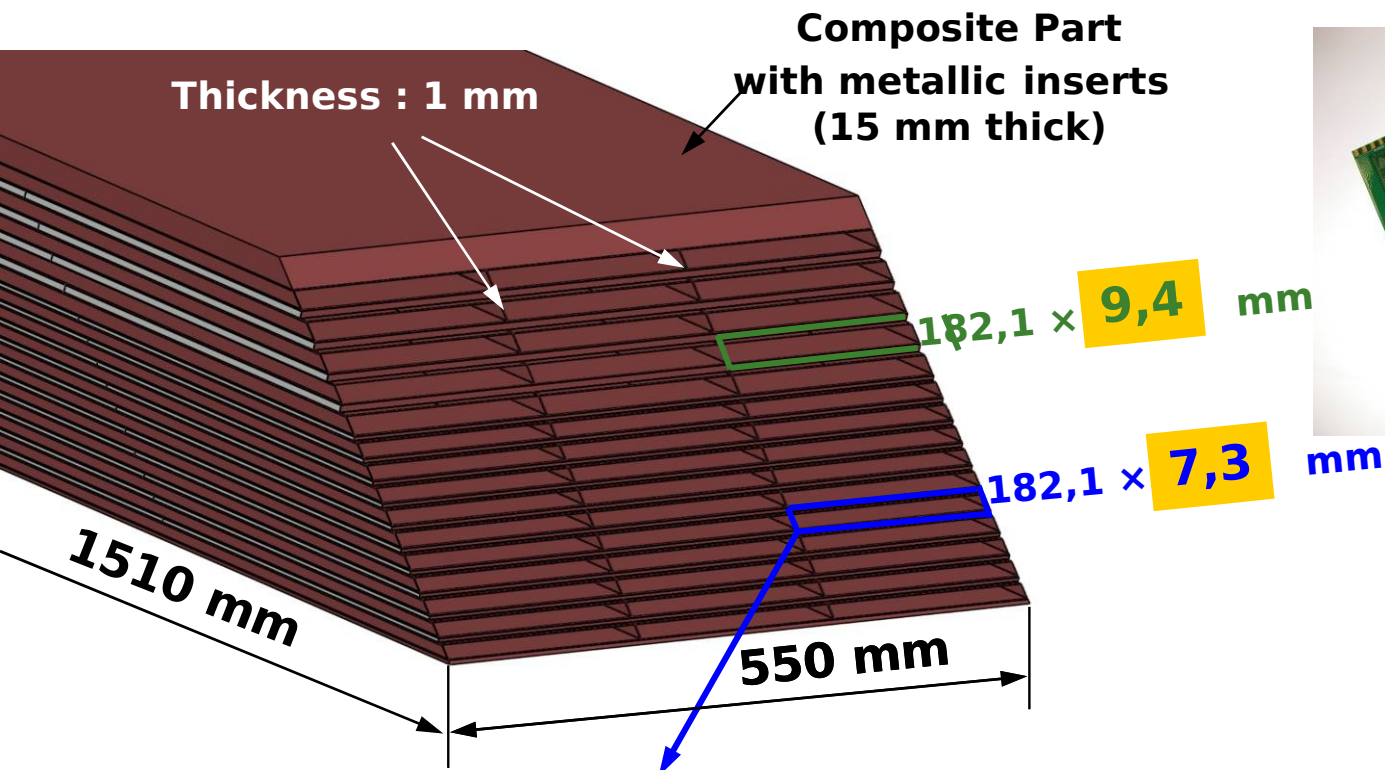
EUDET Memo 2008-11

JRA3 Electromagnetic Calorimeter
Technical Design Report

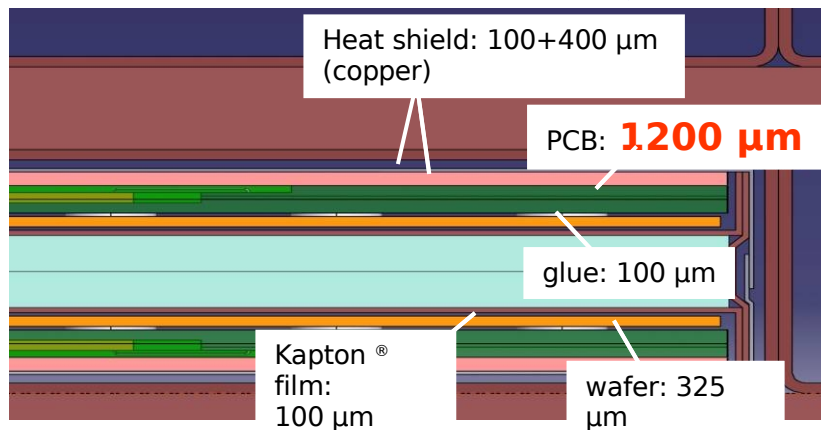
M. Anduze¹, D. Bailey², R. Cornat¹, P. Cornebise³, A. Falou³, J. Fleury³,
J. Giraud⁵, M. Goodrick⁴, D. Grondin⁵, B. Hommels⁴, R. Poeschl³, R. Thompson²

Detailed Technical Design of EUDET Module

Module EUDET – Current Design (final)




Thickness :
 FEV5-1 : 1.17mm (+/-0.04)
 FEV5-2 : 1.19mm (+/-0.04)
 FEV5-3 : 1.20mm (+/-0.02)



- ⇒ Gaps (slab integration) : 500 μm
- ⇒ Heat Shield: 400 μm ? Validation with the demonstrateur
- ⇒ PCB : 800 μm ~~~1200 μm~~
- ⇒ Thickness of Glue : 100 μm
- ⇒ Thickness of SiWafer : 325 μm
- ⇒ Kapton® film HV : 100 μm ?
- ⇒ Thickness of W : 2100/4200 μm ($\pm 80 \mu\text{m}$)


Parties Involved

6 Laboratories are sharing out tasks in according to preferences and localization:

 Assembling of **A.S.U.** (industrialization, gluing and tests) + backend system (DIF support) + services

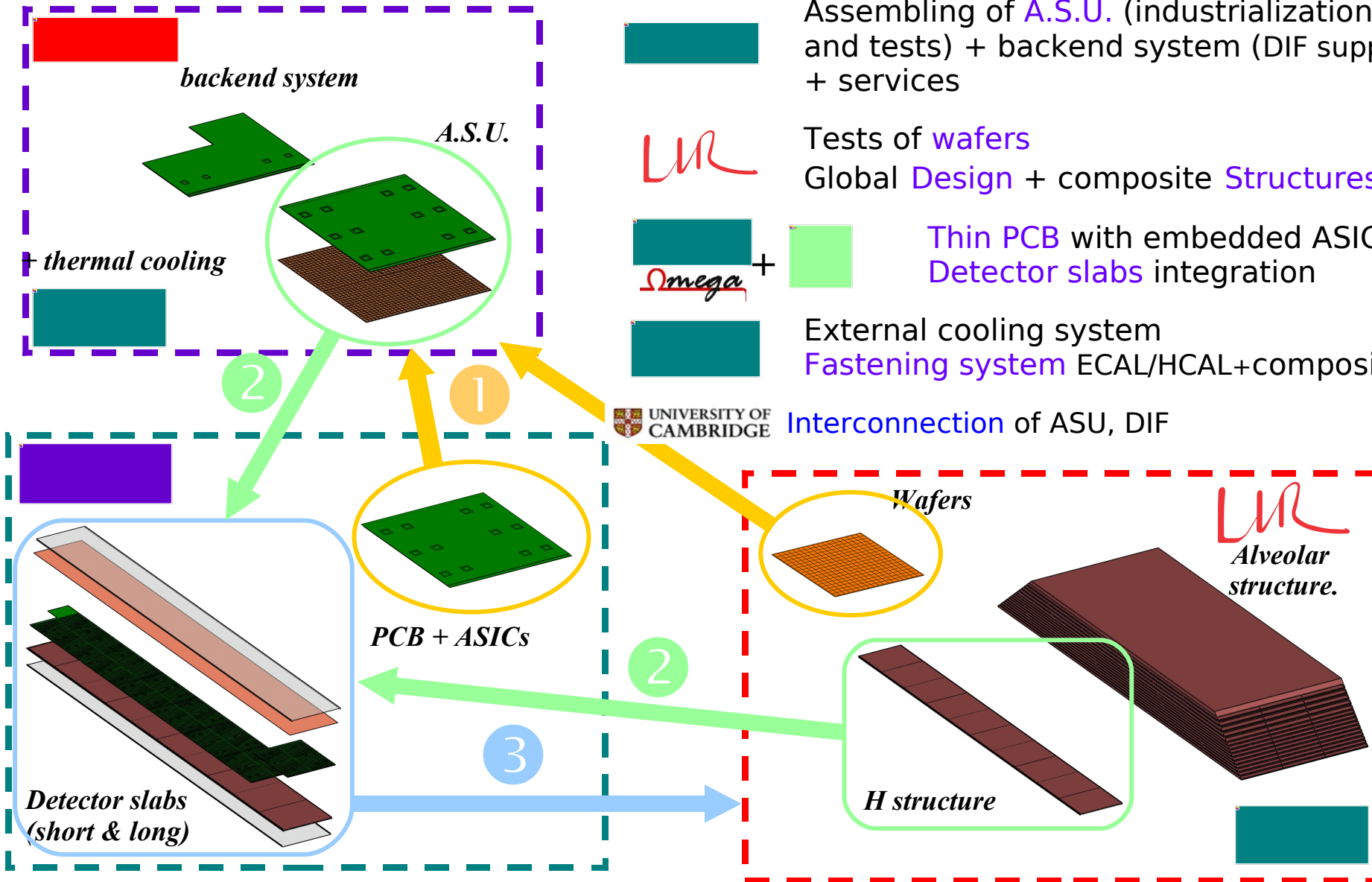
 Tests of **wafers**
Global **Design** + composite **Structures**

 +  Thin **PCB** with embedded **ASICs**
Detector slabs integration

 External cooling system
Fastening system ECAL/HCAL+composite plates



Interconnection of ASU, DIF



Sensors layout

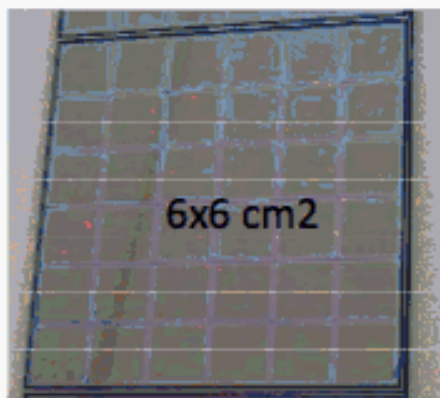
Find a **low cost** but effective sensor

Why ? ILC would need 3000 m² of them

How ? **Smallest number of manufacturing steps**

- PIN diodes
- Guard-rings made with the same steps :
floating guard-rings

- Easy to integrate : gluing
- Low leakage current (<4 nA/cm²)
- Stable in time and for gluing
- $I(V_{bias})$: leakage
- $C(V_{bias})$: depletion and dC/dV noise

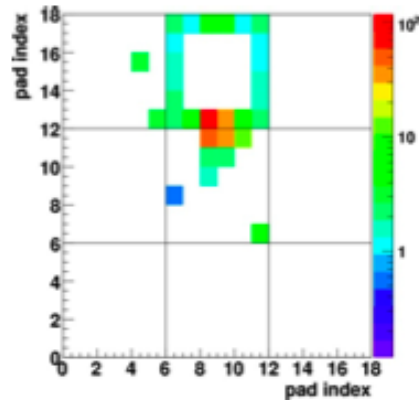


Last prototype :

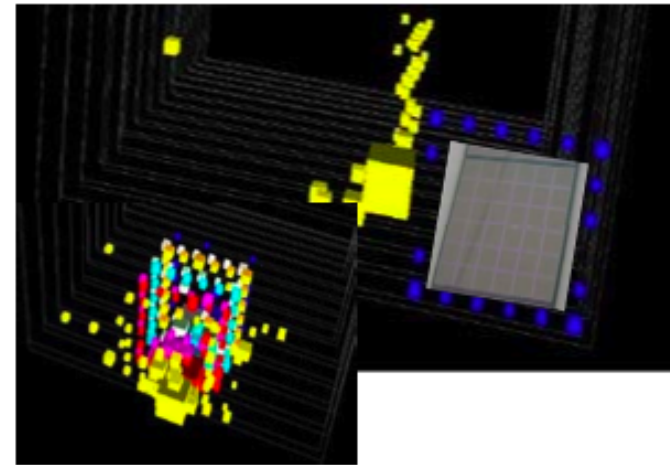
- 3 production batches (2005-2007)
 - Russia (Moscow State University)
 - Czech Republic (Institute of Physics)
 - Korea
- 6x6 pads, 525 um thick, 200V bias
- MIP = 42000 electrons

Cross talk observed during prototype testbeam

When a particle hit the floating guard-rings...



The square shape
corresponds to the guard-
rings location



Unbiased guard-rings act as a pad all around the sensor

Definitely confusing for clustering and reconstruction

Guard-rings are mandatory to avoid breakdown = need to find a
turnaround which meet the cost requirements

- That's (also) what test beams are good for!!!!
- Don't think that you're perfect - Detect the unexpected!!!



In2p3

LNR

Segmented guard rings prototypes preliminary measurements results

- The segmentation of guard rings clearly contributes to the lowering of crosstalk along the edge of the wafers

Continuous			1 cm segments			3 mm segments		
720								
430	220		528	32		170	17	
700	460		50	32	31	29	14	13

- I(V) characteristics are not standard
- Breakdown occurs early, in a 100-300 V range (non segmented: >500 V)
- BUT: no optimizations were done on the layout
 - Further investigations are needed
 - Close contacts with Onsemi: agreement to share the costs



week at Deagu, February 19-20 2009, Rémi Cornat

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- Measurement backed up by theoretical calculations (NSS Proceedings by R. Cornat)
- Pixel cross talk seems to be understood – Conclusive remedies are under study

Hamamatsu wafers

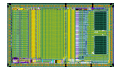
- 9x9 cm², 256 pixels ordered, 40 should be delivered on April
- Cost ! (eur/yen parity)
- 300 μm (may be) gained on the edges
 - 800 μm dead space (1.1 mm in previous version)
- Excellent breakdown >800 V
- Low leakage <4 nA/pixel
 - DC coupling to the chips
 - 1 nA = 1% dynamic range
- Good dC/dV at V_{bias}, <2pF/V (full wafer)
 - Mandatory for noise (CdV + VdC)
 - C= 10E-12, dV=10 mV, V=150V, dC = 20 fF
=> ~400 MIPS...



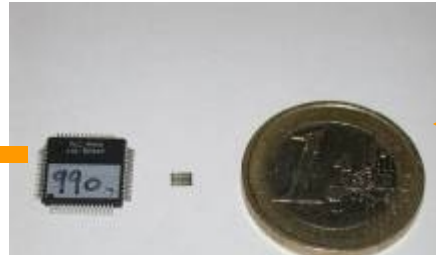
- Wafer Type at hand which meets requirements
- However, vey expensive!!!
- Broaden basis of manufacturers ([FZU \(Cz\)](#), [OnSemi \(CZ\)](#), MSU (Russia), Korea)

SKIROC Chip

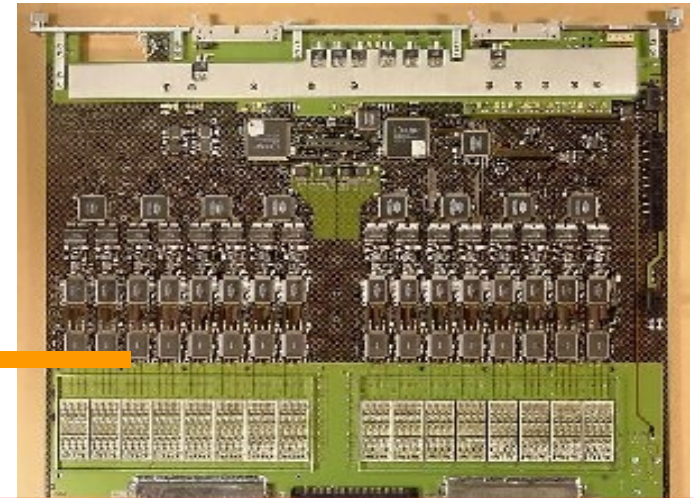
- Designed to read out 64 Channels => 4 Chips per Wafer
- Ultra low power and as small as possible



ILC : **25 μ W/ch**

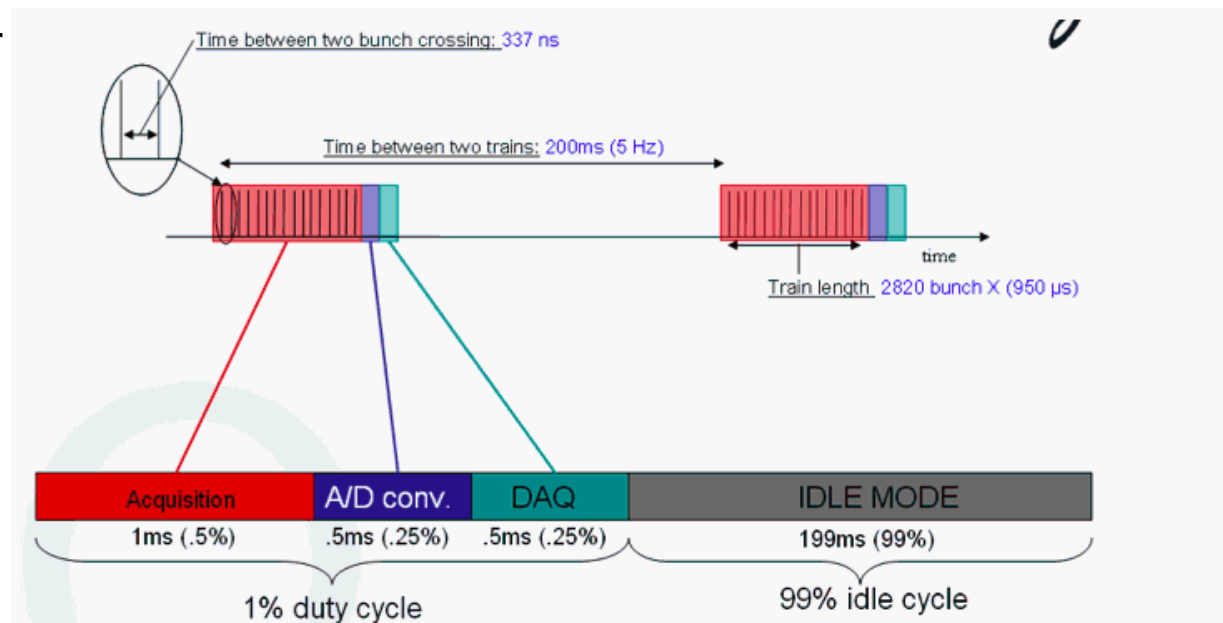


FLC_PHY3 18ch 10*10mm **5mW/ch**

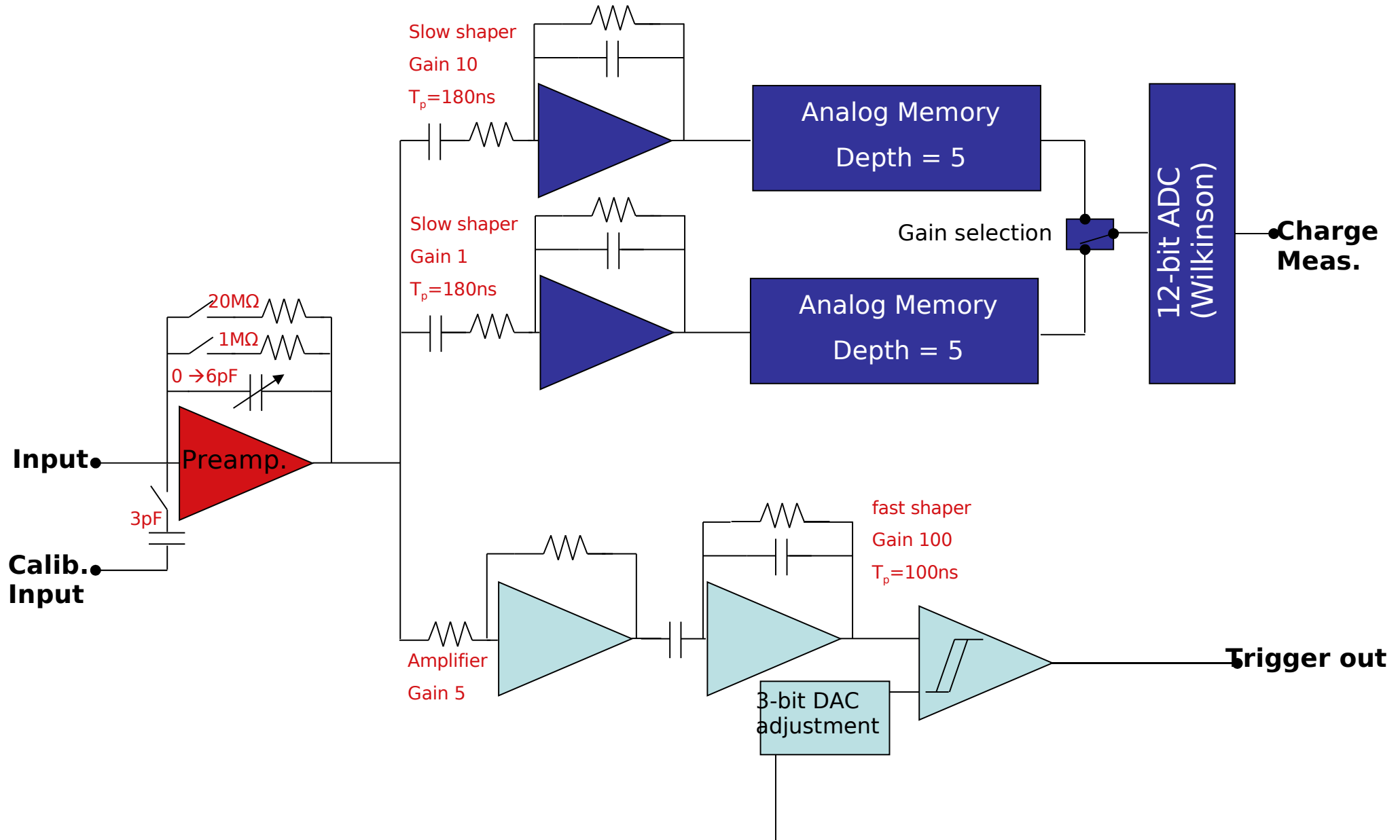


ATLAS LAr FEB 128ch 400*500mm **1 W/ch**

Main “tool” Power Pulsing:

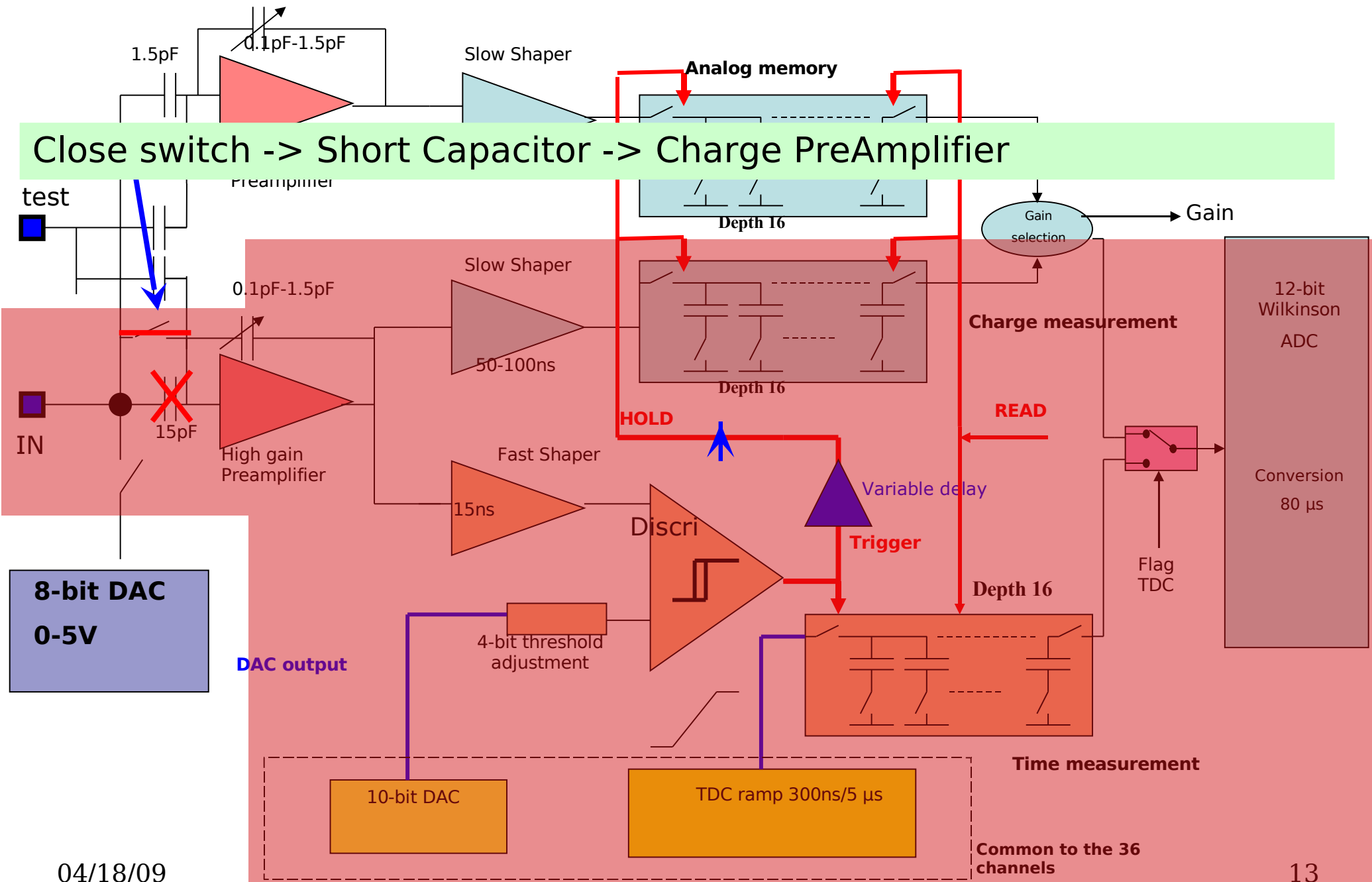


SKIROC1 One channel block scheme



SPIROC used in SKIROC mode

Close switch -> Short Capacitor -> Charge PreAmplifier



04/18/09

TILC09 Tsukuba/Japan April 2009

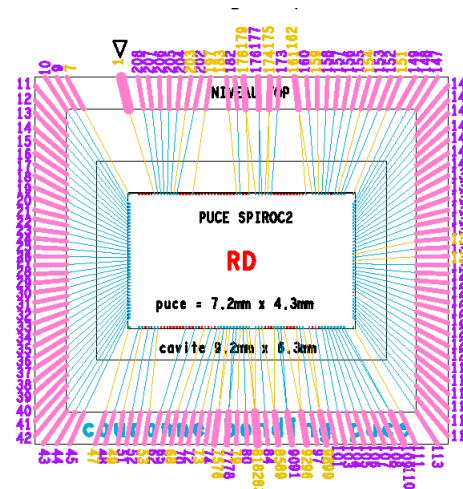
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Printed Circuit Board – Interface between Si Wafers and Chips

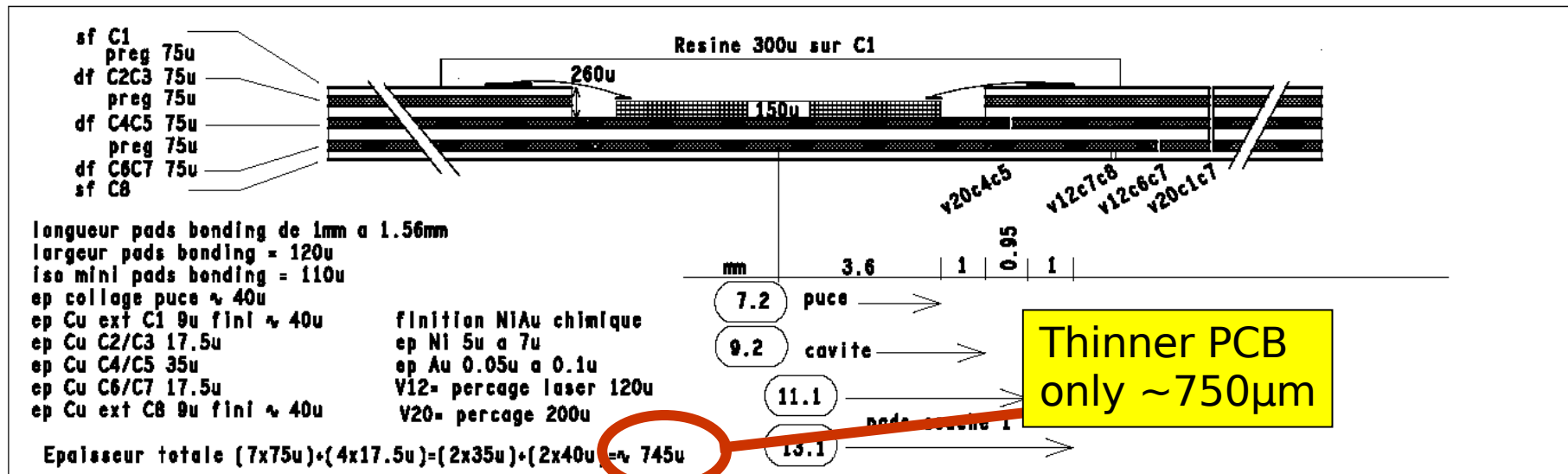
Pile-up

TOP	GND + Input chip signal
C2	horizontal routing
C3	AVDD + DVDD
C4	GND + vertical routing
C5	GND (pads signal shielding)
C6	GND + pads routing
C7	GND (pads shielding)
BOT	PADS

FEV 7



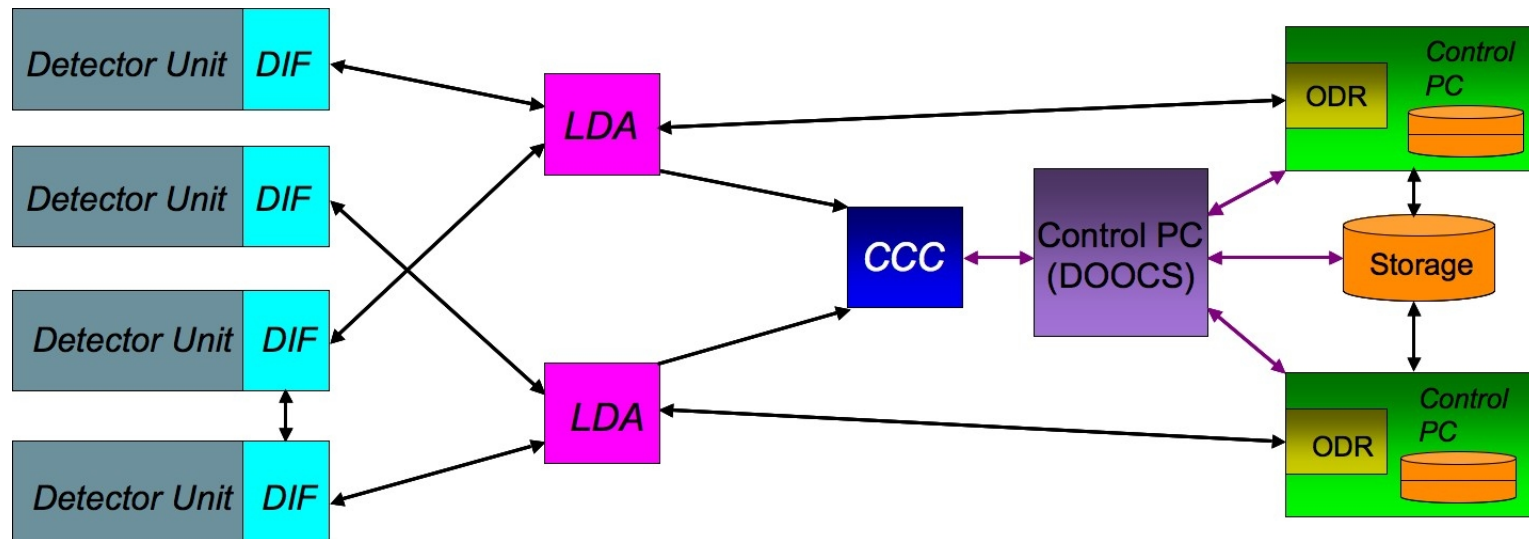
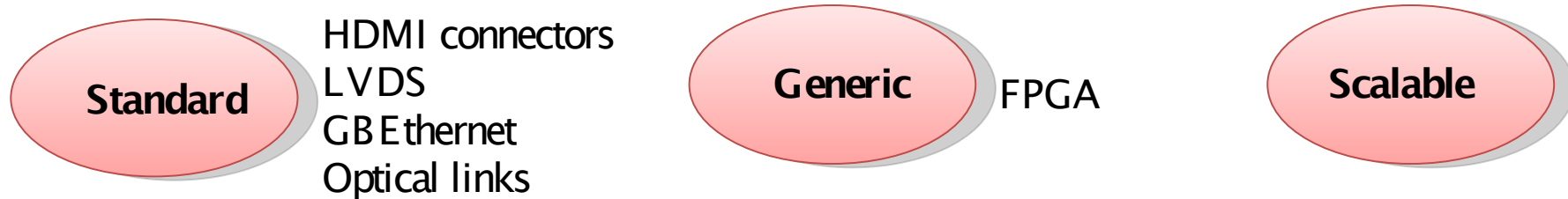
- 4 drilling sequences :**
- Laser C7-C8 120μ filled
 - Laser C6-C7 120μ
 - Mechanical C2-C7
 - Mechanical C4-C5



Very Challenging project – Design under revision

In contact with CERN and Industrial Partners (seems to be beyond industrial standards)

A generic DAQ System

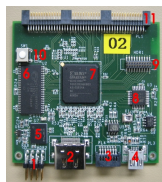
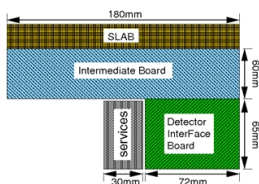


Detector Extremity - Detector Interface Card

Linked Data Aggregator

Clock, Commands and Control

Off Detector Receiver

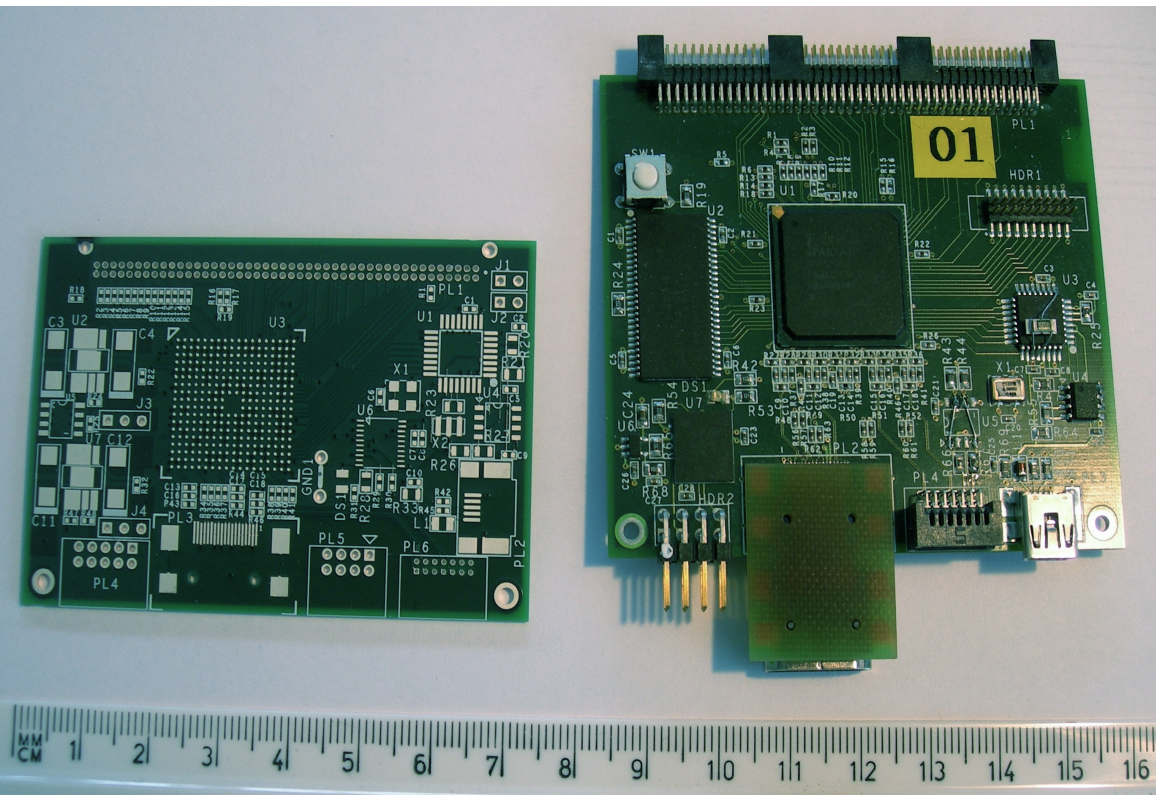


Signal Inputs: <ul style="list-style-type: none"> CLOCK <ul style="list-style-type: none"> 1x LVDS (SMA DC) 1x LVTTTL DC (Lemo) 1x NIM/TTL (Lemo) AC/DC ASYNC <ul style="list-style-type: none"> LVDS (SMA) DC ECL (2 pin LEMO) AC Controls (SYNCCMD, BUSY etc. + more) <ul style="list-style-type: none"> 4x LVDS (SMA) 4x NIM/TTL (Lemo) AC/DC 	Signal Outputs: <ul style="list-style-type: none"> CLOCK <ul style="list-style-type: none"> 2x LVTTTL on Lemo 2x NIM on Lemo 2x LVDS on SMA 8x LVDS on DIL Header TRANSYNCR <ul style="list-style-type: none"> LVTTTL on Lemo GEN (was Busy) <ul style="list-style-type: none"> LVDS on SMA NIM on Lemo CC-TTL on Lemo Spare (DATA, D2L) <ul style="list-style-type: none"> LVTTTL on Lemo 	HDMI I/O: x8 <ul style="list-style-type: none"> LVDS AC/DC CLOCK ASYNC TRANSYNCR IN: <ul style="list-style-type: none"> GEN (was BUSY) SPARE (DATA, D2L)
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ECAL DIF - 2nd revision coming up

Status: 8 DIF prototypes now produced and commissioned



ECAL DIF: small form factor. No room for extra features!

- Xilinx Spartan3 based
- USB, HDMI connections

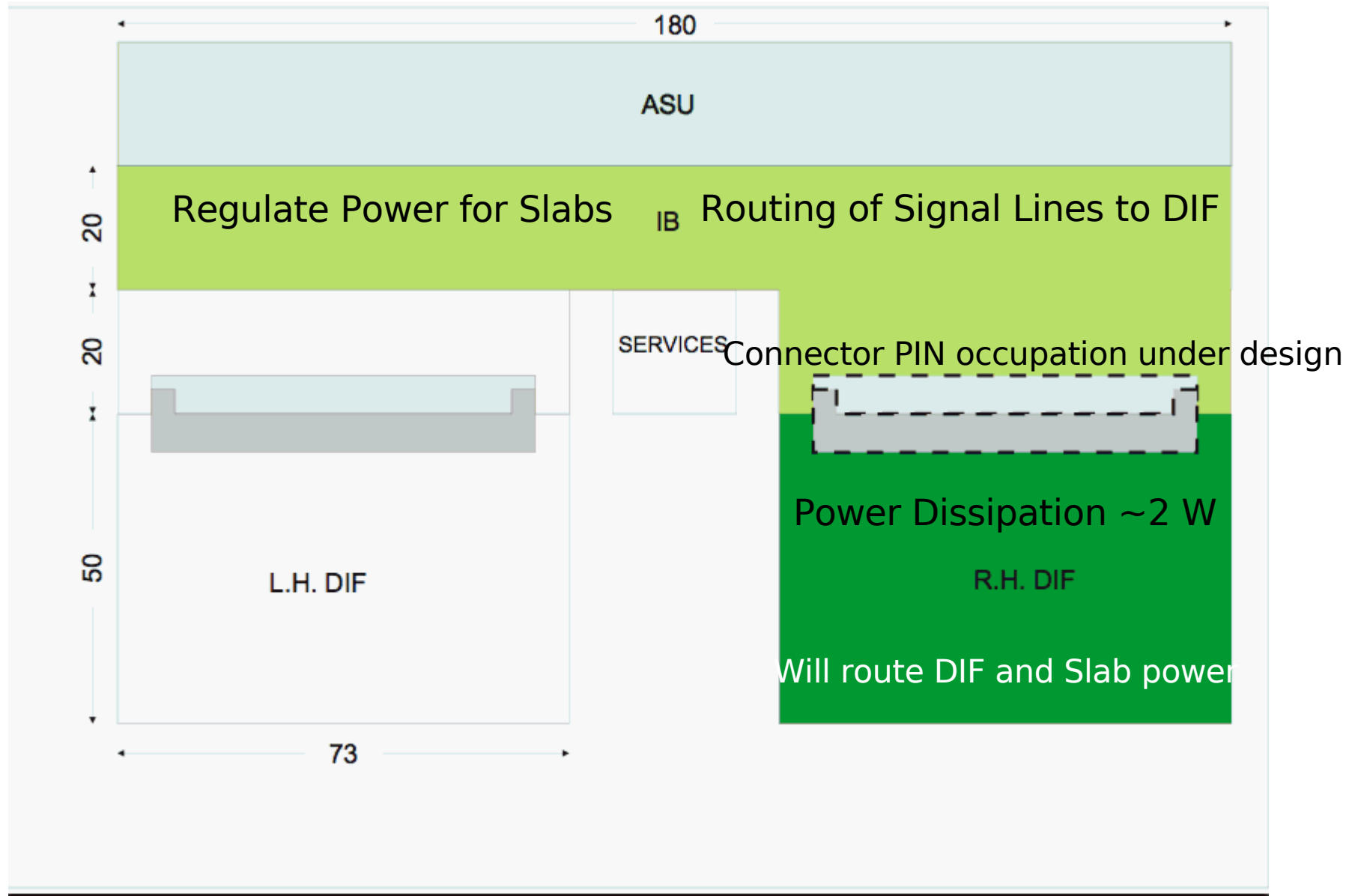
DIF re-spin for EUDET in credit-card size form factor. Main changes:

- No external SRAM, user connector, reset button
- SPI-flash PROM, Flash RAM for VFE config

Hardware status:

PCB designed & produced, some components still being ordered, board population, testing to be done

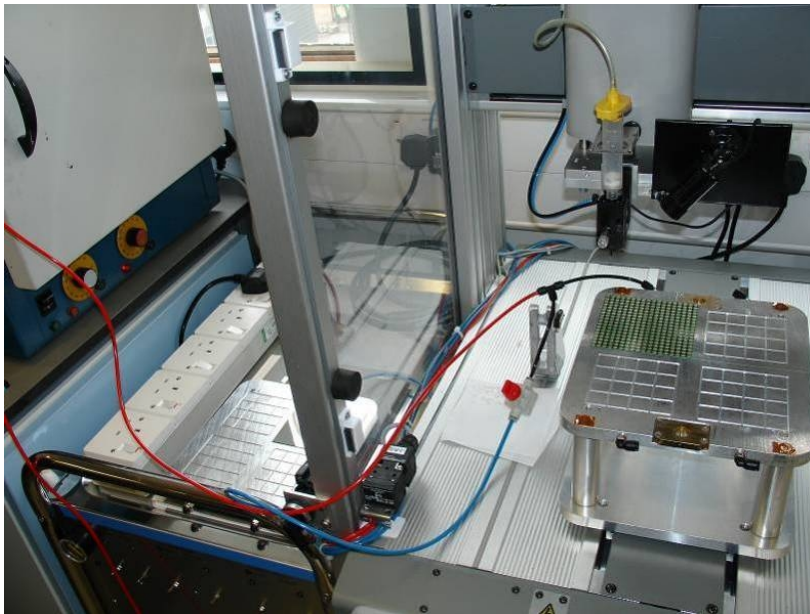
Agreed Dimensions DIF/IB Region



Gluings of ASUS

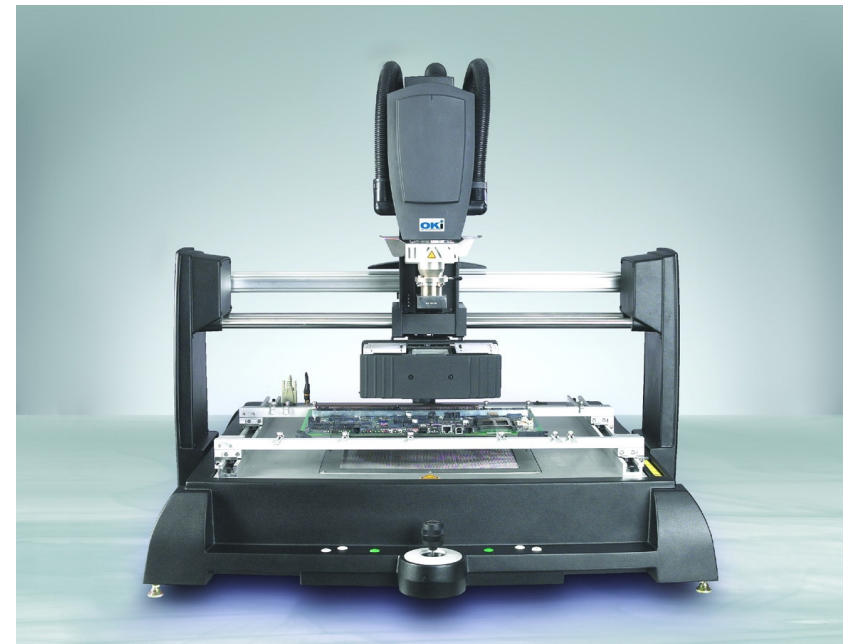
- Controlled glue dot deposition on the PCB
- The (four) Si Wafers are picked up, aligned and placed on the PCB
- Accurate thickness and planarity control via vacuum jigs
- The assembled ASU is allowed to cure

Test board with Dispenser Robot



“Gluings” rate 0.4 Hz

BGA Workstation for Wafer Placement

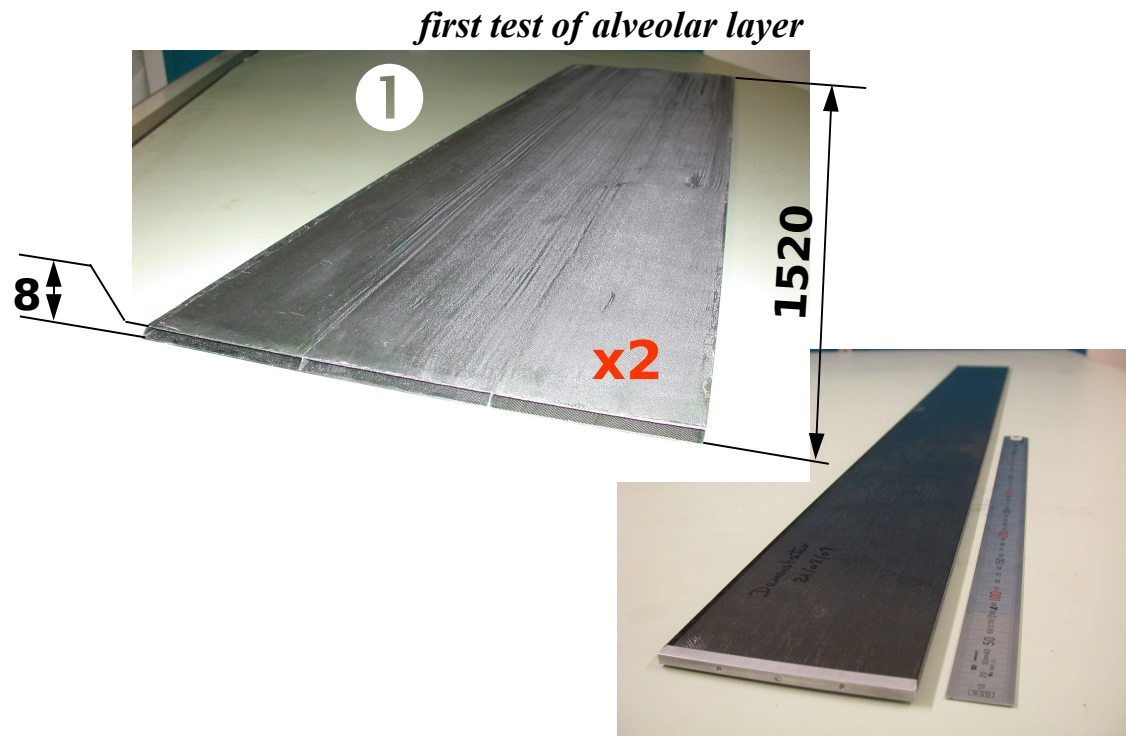
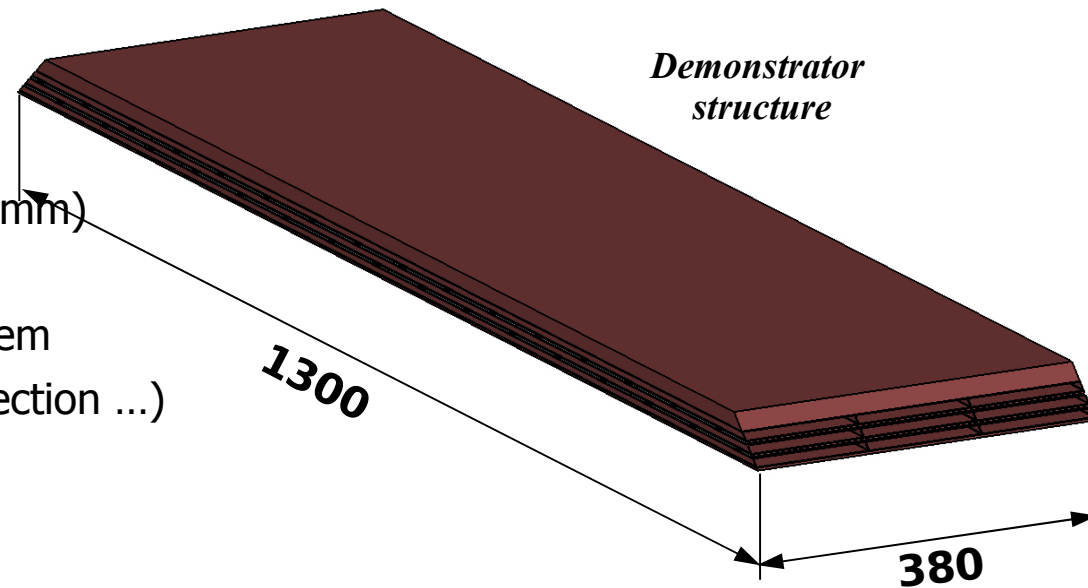


Precise Wafer Placement
by Split Field Optics

ASUs for four thermal layers glued at Uni Manchester

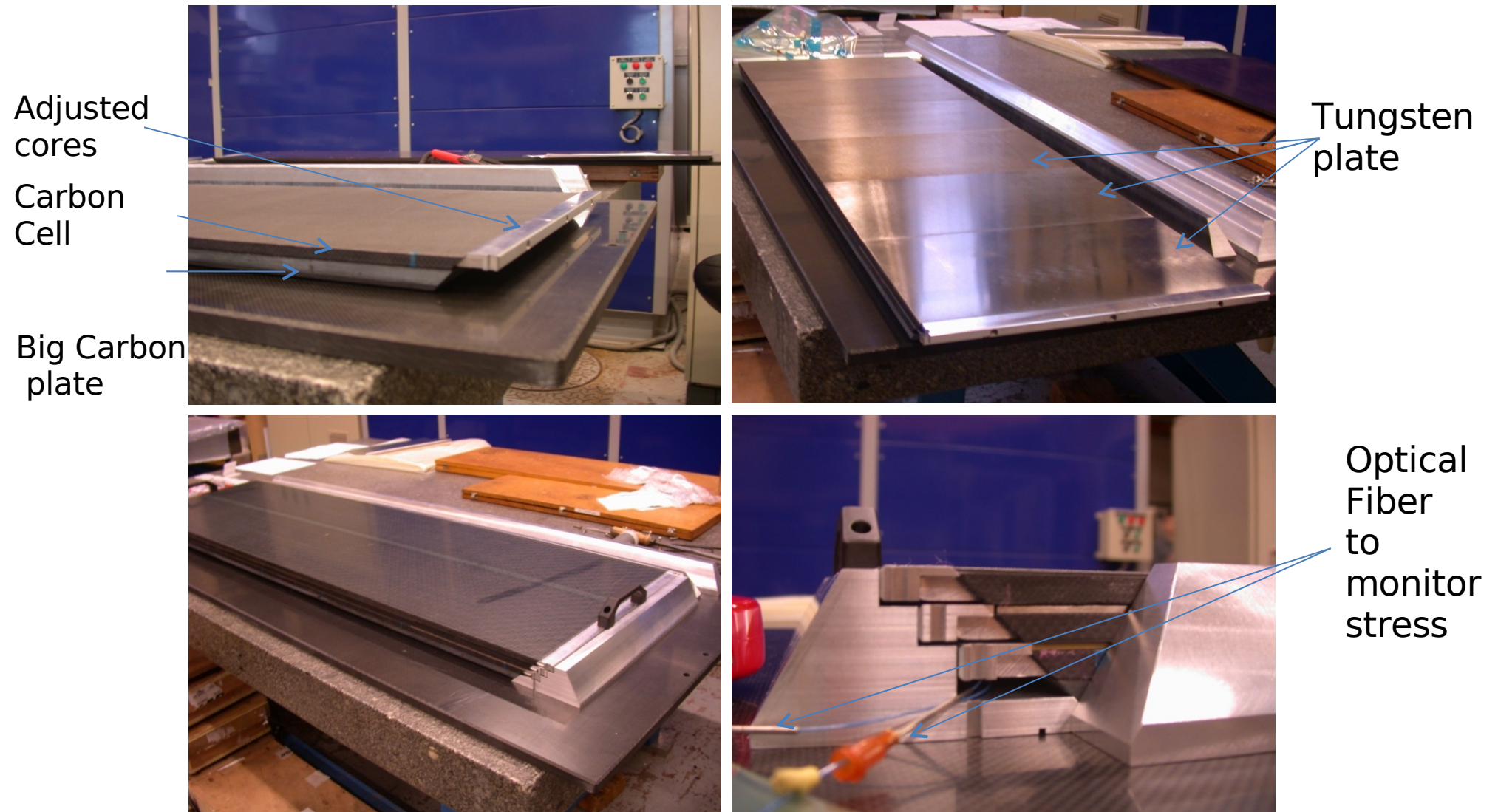
Demonstrator design

- **We have constructed a demonstrator**
validate the assembly process
before the actual EUDET Module
- Width the same as for physics prototype (124 mm)
- **Thermal Studies:**
Equipped with thermal PCBs and a cooling system
- First test of **slab** integration (gluing, interconnection ...)



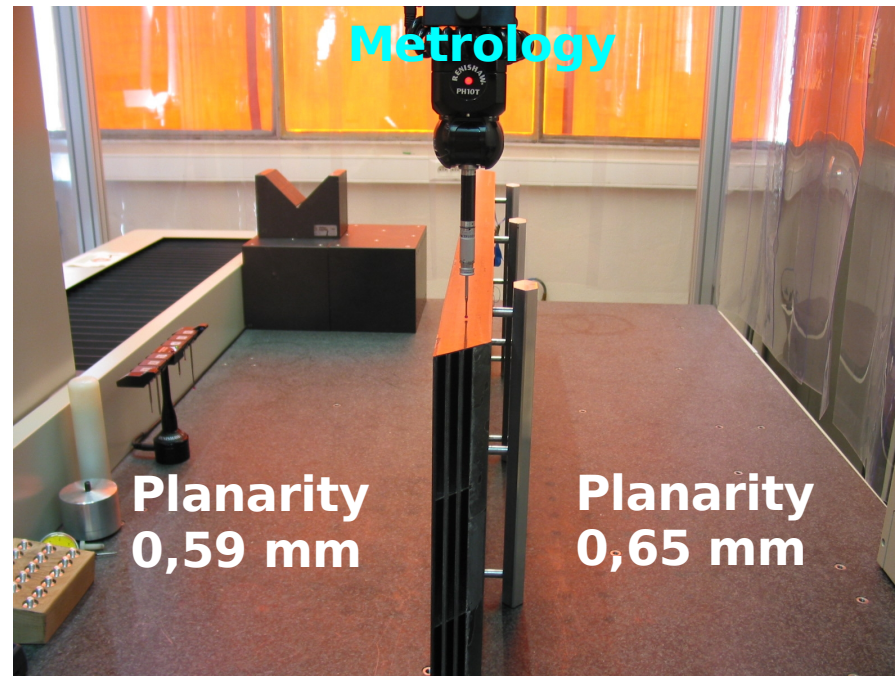
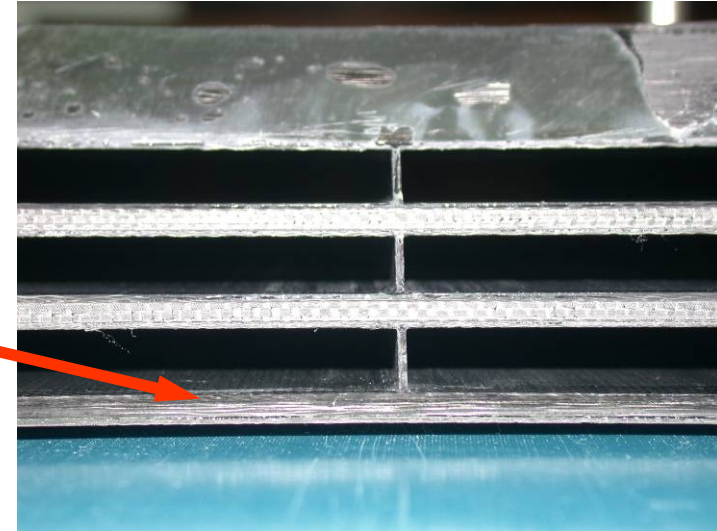
- **3** alveolar layers + **2** W layers
- **3** columns of cells :
representative cells in the
middle of the structure
- **Thermal studies** support
- Width of cells : **126 mm**
- Identical global length : **1.3m**
and shape (trapezoidal)
- Fastening system ECAL/HCAL

Full Assembly



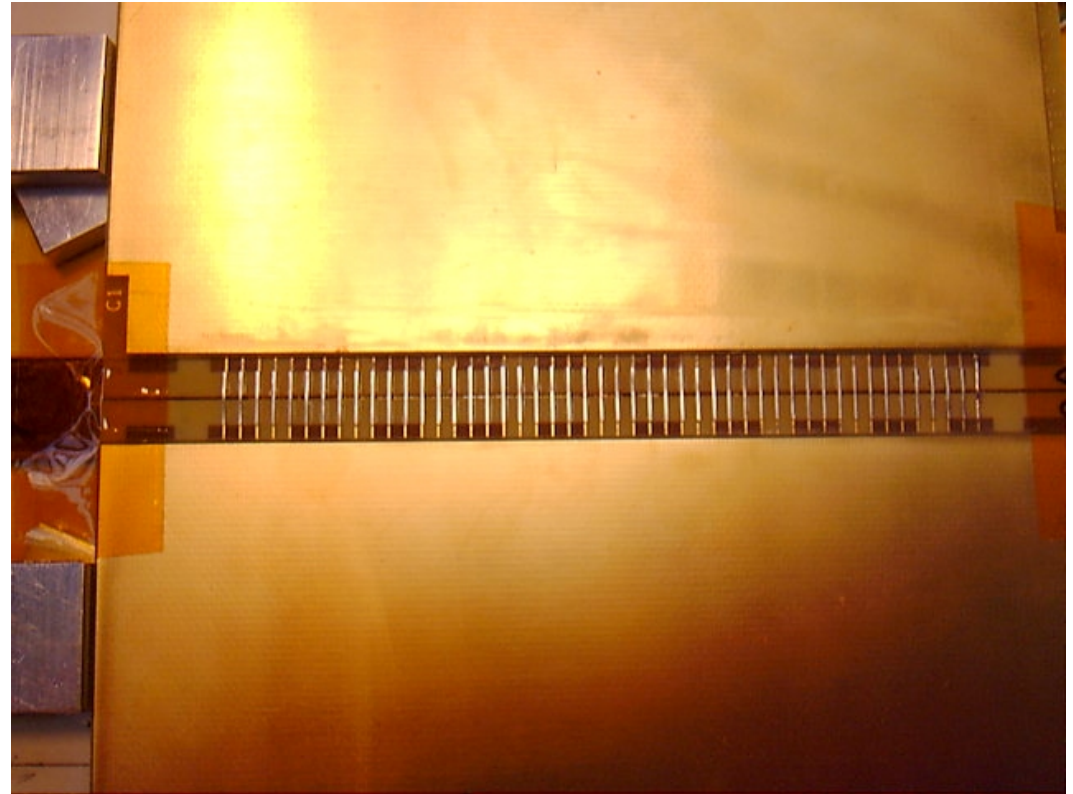
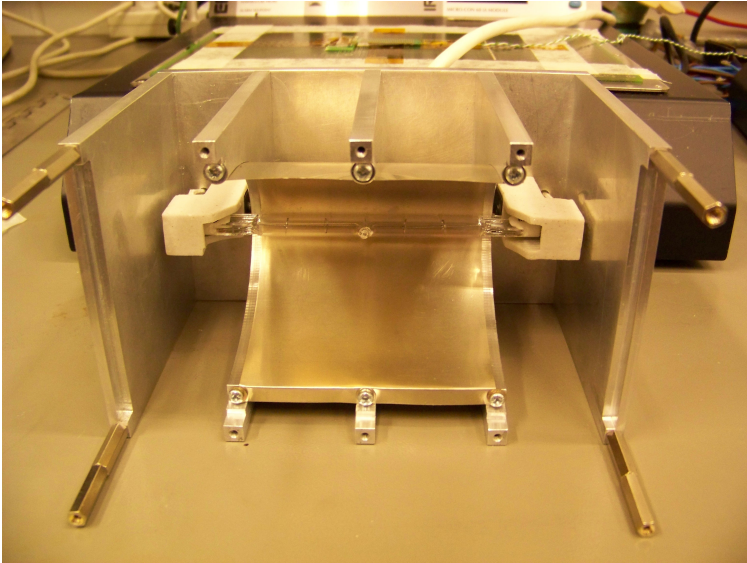
...including Aluminum Cores and Assembly Mould
-> Ready for Curing

Alveolar Structures with (~) ILC Dimensions – **Yes, we can!!!!**

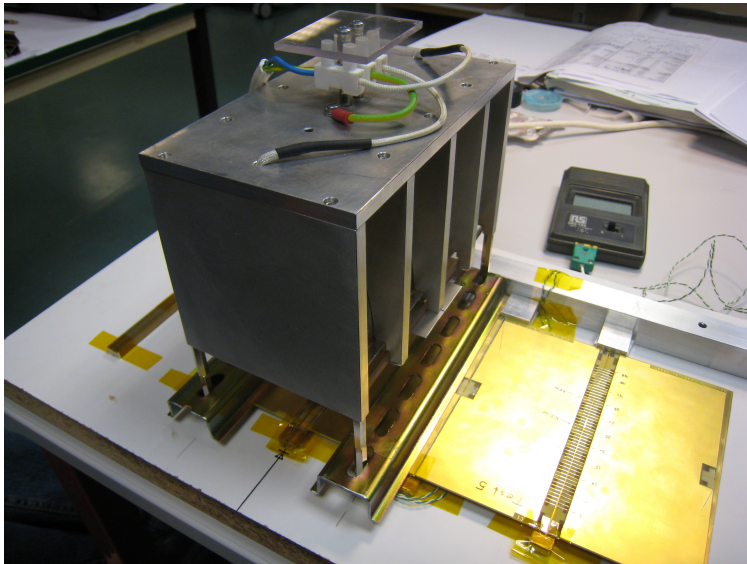


TILC09 Tsukuba/Japan April 2009

The joint between two boards

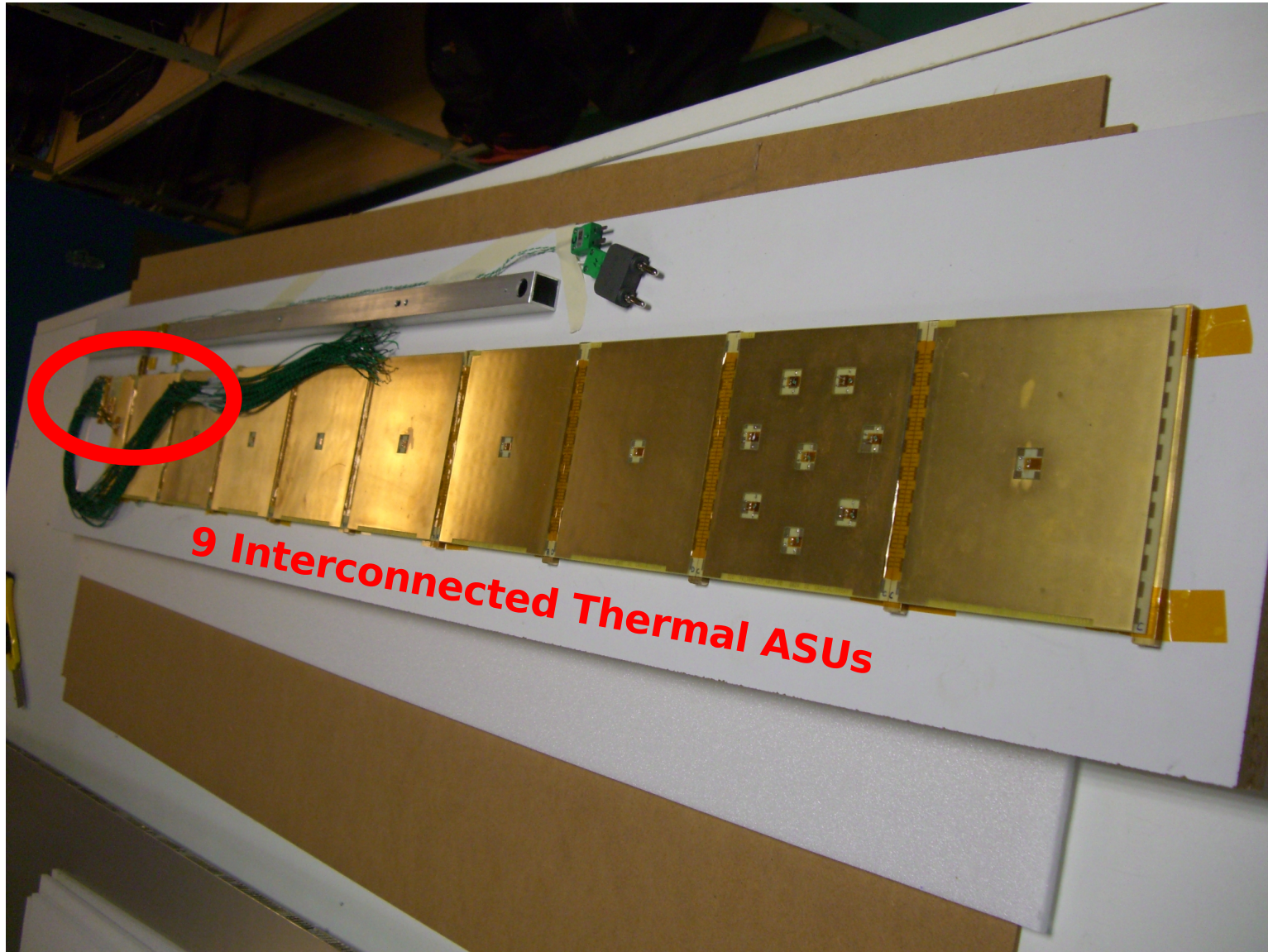


- Joint by halogen lamp heating up tin-bismuth soldering paste
(Method developed by U. Cambridge)
- Heating Temperature $\sim 200^{\circ}\text{C}$



Delicate Process for Demonstrator – Easier for EUDET Module

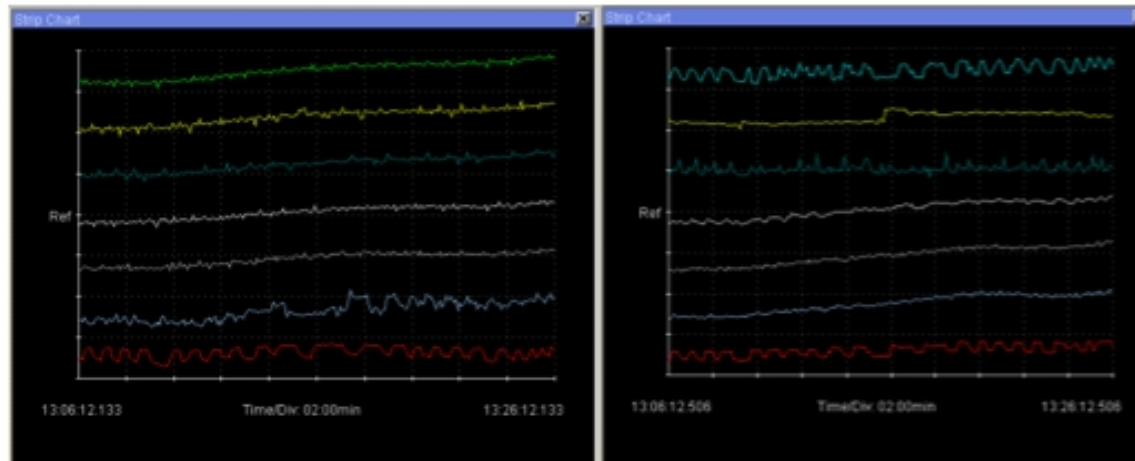
Thermal Layer assembled and ready for Thermal Tests



- w/o Photo: Copper Shielding and CuCe Electrical Protection manufactured at CERN in Collaboration with CALICE

Cooling System: Test Program on going

YES: ALL IS LINEAR
and $\Delta T < 10^\circ\text{C}$!



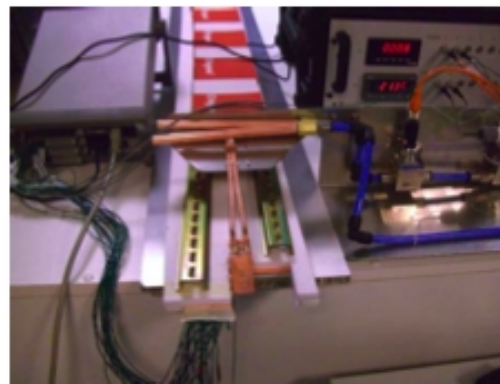
Evolution and correct stabilization of each thermal sensor in response to hot points implementation:

Chips: 0 to 1 W
Int.board: 0 to 1 W
DIF: 0 to 2 W

Extreme test: from Steady state up to cooling failure
=> temperature curve increasing to determine the maximal acceptable time without cooling (info for Elec...)



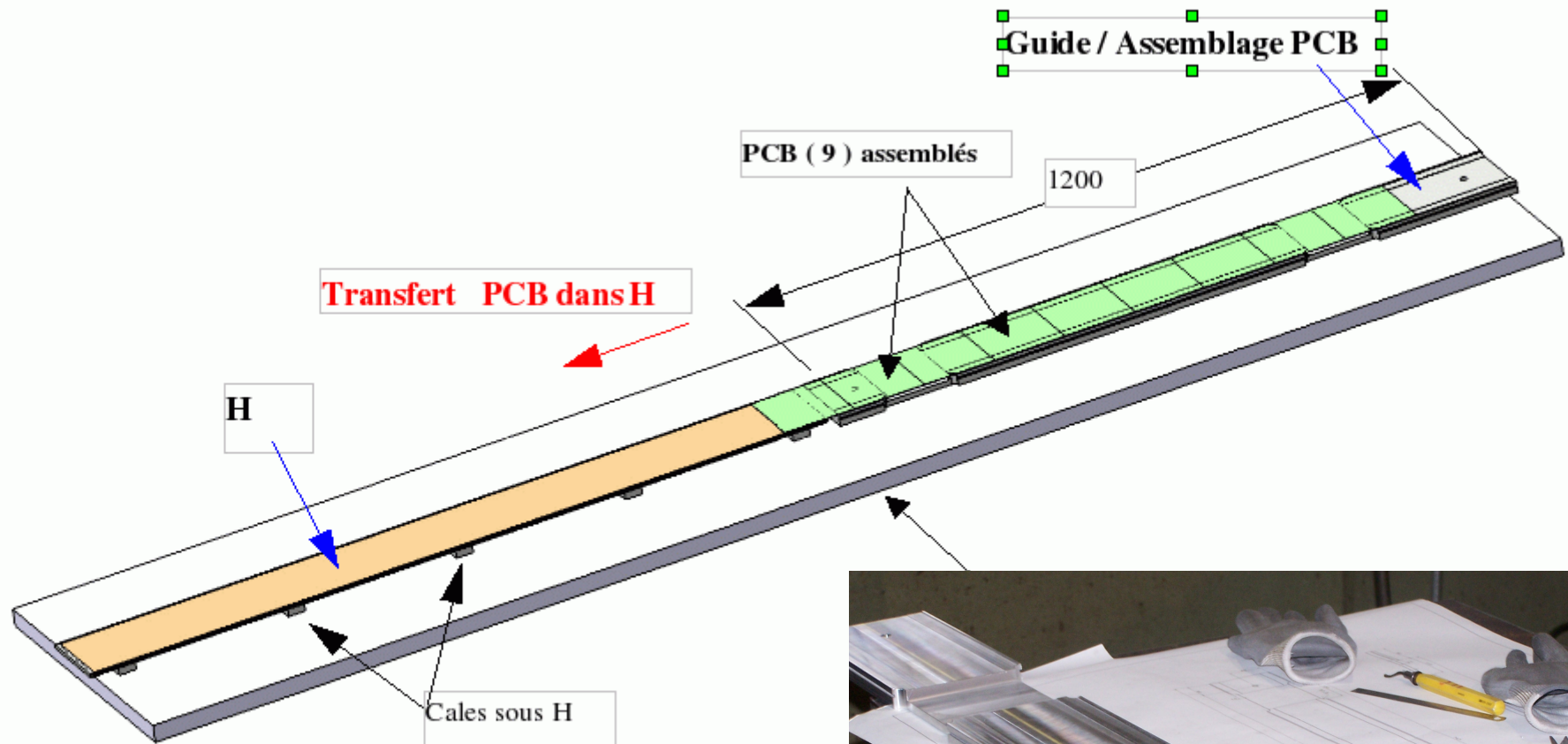
Boards assembled



⇒ Design : **OK**
⇒ Simulations : **OK**
⇒ Copper plate : **OK**
⇒ Interconnect : **OK**
⇒ Exp. setup : **OK**

Next tests with EUDET structure

- First test measurements did validate simulation
- However conclusions compromised by convection in workshop and not optimal thermal contacts with copper drain
- Optimisation studies ongoing – Continuation of tests Middle of May 09



Conclusion and Outlook

- Technical Design finished in Oct. 2008

Preparation and conduction of Demonstrator Tests since then

- In the middle of the studies with the demonstrator

- First measurement for thermal analysis
- Assembly of alveolar structure finished
- Integration cradle for long slab ready
- Revision of thermal drain ongoing

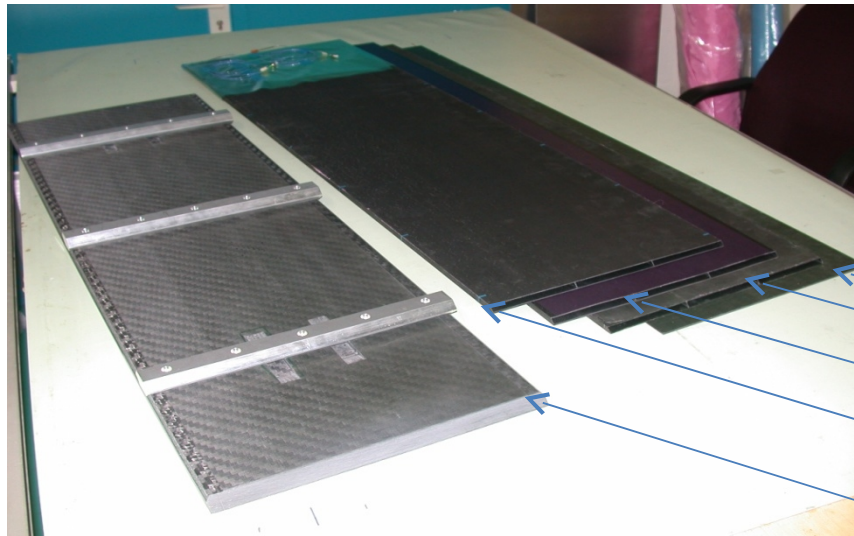
Demonstrator studies finished by July 2009
Will cover most if not all mechanical aspects
described in EUDET proposal

Conclusion and Outlook cont'd

- Towards the EUDET Module
 - Construction of H Structures and alveolar layers seems feasible
Demonstrator can be extrapolated to full blown structure
 - “Wrapping” of Slab and Integration Cradle for 'real' slab
 - First prototype in hand - needs further study
 - needs special tools which are very expensive!!!!
- Excellent progress concerning Si Wafers
 - Wafers according to specs available (However expensive)
 - Corss talk problem understood
- Focus of getting the VFE accomplished in (early) 2010
- “Shipping” signals out
Interface to the DAQ and beyond will be advancing

First Assembly of the Alveolar Structure for the Demonstrator

Mechanical Structure only slightly smaller than for EUDET Module



Small Plate
Cell structure N°1
Cell structure N°2
Cell structure N°3
Big Carbon plate



Final Temporary assembly

All pieces for mechanical housing of "Demonstrator" Slabs available

SPIROC in ECAL

- Limitations :
 - Dynamic range :
 - 500 MIP/cell → same as physics prototype
 - Number of channels :
 - 36 channels instead of 64 → lower granularity